

Applied Materials Endura 5500 Adhesion CVD

- Manufacturer: Applied Materials
- Model: 5500
- Wafer Size: 200mm
- Cleanroom Interface: Endura HP Front Panel
- Controller: PVD Endura Type Controller 55-5-1030-B
- VME PC Hardware
- VHP Transfer Robot: VHP Robot 55-6-1036
- HP Buffer Robot
- Deep Pocket Transfer Blade & Metal Buffer Robot Blade
- Standard SECS RS 232 Communication 55-8-1045

CHAMBER 1

- Titanium PVD Widebody Chamber
- CTI Fast Regen Enhanced Cryo Pump 3-phase (subject to availability)
- 12kW CEM Master PVD Power Supply
- PVD Wafer Chuck: Unclamped
- IMP Advanced 101 Type Pedestal- VECT-P1-5072
- Mag Coupled Shutter, VOR Match
- HP Motorized Lift
- PVD Pressure Control: 3 Position Gate Valve
- Cryo Restrictors
- PVD Chamber Safety Option: EMO On Source Cover
- Chamber Lid Clamp Lever Extension
- SST Cover Ring
- Shield Material & Type Option: Aluminum One Piece
- Short Detect w/Impedance Network

CHAMBERS 2/3

- (2) HP TxZ CVD Titanium-Nitride Chambers- HP TxZ-m3
- BC hardware/TxZ heaters
- Heater Power Cables- 0150-76286

CHAMBER A

- Pass-Through Chamber
- Quartz Viewport Lid

CHAMBER B

- Cooldown Chamber
- Quartz Viewport Lid

CHAMBER C/D

- (2) Preclean II Chambers

CHAMBER E/F

- (2) Orienters with Enhanced Degas – 55-E/F-5748